



IN THE U.S. PATENT AND TRADEMARK OFFICE

17W

Applicant(s): Horacio D. ESPINOSA et al.

For: NANOTIPPED DEVICE AND METHOD

Serial No.: 10/801 928 Group: 3754

Confirmation No.: 2330

Filed: March 16, 2004 Examiner: Unknown

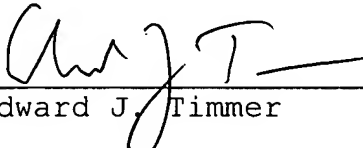
Atty. Docket No.: NU23014

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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Sir:

I hereby certify that this correspondence is being deposited with the United States Postal Service under 37 CFR 1.8 as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on July 28, 2004.



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Correspondence: Information Disclosure Statement including
enclosures listed thereon



PATENT APPLICATION

July 27, 2004

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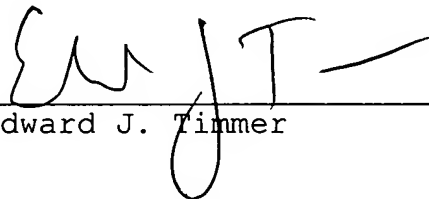
INFORMATION DISCLOSURE STATEMENT

Sir:

This Information Disclosure Statement is being filed in accordance with the duty of disclosure under 37 C.F.R. § 1.56 and pursuant to 37 C.F.R. § 1.97-1.98. Enclosed herewith is Form PTO-1449 including copies of the documents listed under the heading "Other Documents." Accordingly, further comment at this point in time should not be necessary.

Further consideration is respectfully solicited.

Respectfully submitted,



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INFORMATION

Applicant : Horacio D. Espinosa et al.

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DISCLOSURE

Serial No. : 10/801 928

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U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Name	Class	Sub Class	Filing Date

FOREIGN PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Country	Class	Sub Class	Translation Y/N

OTHER DOCUMENTS (Including Author, Title, Date, Pages, Etc.)

AA	de Boer, M. et al., "Micromachining of Buried Channels in Silicon," J. Microelectromech. 9(1), Mar 2000, p. 94-103.
AB	Hong, M. et al., "Scanning nanolithography using a material-filled nanopipette," Appl. Phys. Lett. 77(16), Oct 2000, p. 2604-2606.
AC	Hong, S. et al., "A Nanoplotter with Both Parallel and Serial Writing Capabilities," Science 288, June 2000, p. 1808-1811.
AD	Lewis, A. et al., "Fountain pen nanochemistry: Atomic force control of chrome etching," Appl. Phys. Lett. 75(17), Oct 1999, p. 2689-2691.
AE	Lieberman, K. et al., "Multifunctional, micropipette based force cantilevers for scanned probe microscopy," Appl. Phys. Lett. 65(5), Aug 1994, p. 648-650.
AF	Minne, S. et al., "Automated parallel high-speed atomic force microscopy," Appl. Phys. Lett. 72(18), May 1998, p. 2340-2342.
AG	Minne, S. et al., "Centimeter scale atomic force microscope imaging and lithography," Appl. Phys. Lett. 73(12), Sep 1998, p. 1742-1744.
AH	Papautsky, I. et al., "Micromachined Pipette Arrays," IEEE Trans. Biomed. Eng. 47(6), p. 812-819.

EXAMINER

DATE CONSIDERED

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INFORMATION	Applicant : Horacio D. Espinosa et al.	Page 2 of 2
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Examiner Initial*	Document Number	Date	Country	Class	Sub Class	Translation Y/N

OTHER DOCUMENTS (Including Author, Title, Date, Pages, Etc.)

AI	Piner, R. et al., "'Dip-Pen' Nanolithography," Science 283, Jan 1999, p. 661-663.
AJ	Rangelow, I. et al., "'NANOJET': Tool for the nanofabrication," J. Vac. Sci. Technol. B 19(6), Nov/Dec 2001, p. 2723-2726.
AK	Shalom, S. et al., "A micropipette force probe suitable for near-field scanning optical microscopy," Rev. Sci. Instrum. 63(9), Sep 1992, p. 4061-4065.
AL	Vettiger, P. et al., "The 'Millipede' - More than one thousand tips for future AFM data storage," IBM J. Res. Develop. 44(3), May 2000, p. 323-340.
AM	Vettiger, P. et al., "The 'Millipede' - Nanotechnology Entering Data Storage," IEEE Trans. on Nanotech. 1(1), Mar 2002, p. 39-55.
AN	Zhang, M. et al., "A MEMS nanoplotter with high-density parallel dip-pen nanolithography probe arrays," Nanotechnology 13, 2002, p. 212-217.
AO	Zou, J. et al., "Conductivity-based contact sensing for probe arrays in dip-pen nanolithography," Appl. Phys. Lett. 83(3), Jul 2003, p. 581-583.

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